



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. .... 10/664,744  
Filing Date ..... September 18, 2003  
Inventor ..... Michael T. Andreas  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2823  
Examiner ..... Fernando L. Toledo  
Attorney's Docket No. .... MI22-2335  
Title: Method of Polishing a Semiconductor Substrate, Post-CMP Cleaning  
Process, and Method of Cleaning Residue from Registration Alignment  
Markings

**RESPONSE AFTER JANUARY 4, 2005 NOTICE OF ALLOWANCE**  
**PRELIMINARY AMENDMENT TO ACCOMPANY RCE FILING**

To: Mail Stop RCE  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**VIA EXPRESS MAIL**

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)  
Wells St. John P.S.  
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Spokane, WA 99201-3828

Responsive to the Notice of Allowance dated January 4, 2005, Applicant  
remarks as follows: